



Match & Return

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATO, et al.

Serial No.: 09/461,432

Filed: December 16, 1999

For: VACUUM PROCESSING APPARATUS AND OPERATING METHOD THEREFOR

Group: 3749

Examiner: S. Gravini

Allowed: December 7, 2000

Batch No.: W11

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(NE)
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PK to enter
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AMENDMENT UNDER 37 CFR 1.312

Assistant Commissioner for Patents
Box Issue Fee
Washington, D.C. 20231

January 18, 2001

Sir:

Please amend the above-identified application, subsequent to issuance of the Notice of Allowance mailed December 7, 2000, as follows:

IN THE CLAIMS

Please amend the claims presently in the application as follows:

1. (Amended) A method of using a conveyor system for processing substrates in plural vacuum processing chamber installation portions, the conveyor system including:

- an atmospheric loader, exposed to the air;
- a vacuum loader; and
- a lock chamber, having an atmospheric loader side

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